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IEE CNF	IEE Conference Proceeding		Zawadzka, J.; Li, L.; Uttamchandani, D.; Science, Measurement and Technology, IEE Proceedings-
IEEE STD	IEEE Standard	•	Volume 151, Issue 2, 3 March 2004 Page(s):61 - 66
			Digital Object Identifier 10.1049/ip-smt:20040180 <u>AbstractPlus</u>   Full Text: <u>PDF(</u> 397 KB)   <b>IEE JNL</b>
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